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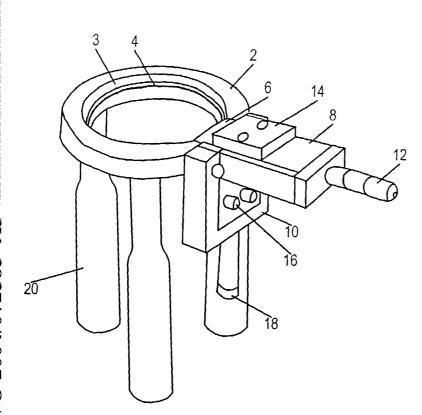
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[Continued on next page]

(54) Title: WAFER BOND STRENGTH EVALUATION APPARATUS



(57) Abstract: An apparatus and method for measuring bond strength of a bonded wafer that allows for reliable and reproducible measurements, thereby allowing a better comparison of bond strengths of various wafers. A wafer receptacle (2) holds the bonded wafer (28) to be measured securely in place. A Z-axis adjustment device (10) with precision actuator is adjusted to align a blade with bond interface of the bonded wafer. An X-axis adjustment device (8) with precision actuator (18) connected to a spring is adjusted to introduce the blade into bond interface creating a crack, the length of which can be measured and used to determine bond strength. The stability and precision introduced by the Z-axis and X-axis adjustment devices also increase the reliability and reproducibility of the bond strength measurement.

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Electronic data base consulted during the international search (name of data base and, where practicable, search terms used) Please See Continuation Sheet			
C. DOCUMENTS CONSIDERED TO BE RELEVANT			
Category * Citation of document, with indication, where a	oppropriate, of the relevant passages R	elevant to claim No.	
A US 5,275,489 A (BORNEMAN et al) 04 January 19	994 (04.01.1994), see the entire patent.	1-12	
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A US 6,689,245 B2 (TSUJIMOTO) 10 February 2004 (05.02.2004, see the entire Patent.		1-12	
Further documents are listed in the continuation of Box C. See patent family annex.			
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